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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

PATENT

Applicants:	Nishio, et al.	Docket No.:	49288.2800
Serial No.:	10/595,201	Examiner:	Laura M. Lee
Filed:	January 2, 2007	Group Art Unit:	3724
Title:	SUBSTRATE DICING SYSTEM, SUBSTRATE MANUFACTURING APPARATUS, AND SUBSTRATE DICING METHOD	Confirmation No.:	4462

AMENDMENT AND REPLY

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Commissioner:

In reply to the Office Action dated April 14, 2010, of which this Reply is filed within three months, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims, which begins on page 2 of this paper.

Remarks/Arguments begin on page 5 of this paper.

DO NOT ENTER: /L.L./

07/14/2010